

S/N TBD
Docket: CS03 - 039
Group art unit : ____ TBD

Date 11/21/2003

To: **Commissioner of Patents and Trademarks**
P.O. Box 1450 Alexandria, VA 22313-1450

Fr: **William J. Stoffel Reg. No. 39,390 Cust No. 30402**
PMB 455
1735 Market St - Suite A
Philadelphia, PA 19103

Subject:

Serial No. TDB
Docket CS03 - 039
File Date: with application
Inventor: Chen

**title: CMP Polishing Heads Retaining Ring Groove
Design for Microscratch Reduction**

Group art unit: TBD

INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO A820 (also PTO-1449), Information Disclosure Citation and references.

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450, on Nov 24, 2003.

Signature/Date William J. Stoffel

William J. Stoffel Reg. No. 39,390
Customer number 30402

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The following Patents and/or Publication are submitted to comply with the duty to disclose under CFR 1.97-1.99 and 37 CFR 1.56.

US 6,386,962B1(Gotkis et al.) that shows a wafer carrier with retainer ring for a chemical-mechanical polish (CMP) apparatus.

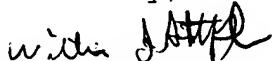
US 6,527,624 B1(Tollers et al.) shows a retaining ring.

US 6,110,025(Williams et al.) teaches a retainer ring with passages.

US 6,293,850 B1(Lin et al.) shows retaining ring with slurry passages at the bottom of the retainer ring.

US 6,224,472 B1(Lai et al.) teaches a retaining ring with channels.

Sincerely,



William J. Stoffel
Reg. No. 39,390
Customer number 30,402

INFORMATION DISCLOSURE CITATION <i>(Use several sheets if necessary)</i>				Docket Number (Optional) cs03-039		Application Number 	
				Applicant(s) chen et			
				Filing Date 		Group Art Unit 	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
		US 6,386,962 B1		(Gotkis et al.)			
		US 6,527,624 B1		Tollers et al.)			
		US 6,110,025		Williams et al.)			
		US 6,293,850 B1		Lin et al.)			
		US 6,224,472 B1		Lai et al.			
FOREIGN PATENT DOCUMENTS							
REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO
OTHER DOCUMENTS <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>							
EXAMINER				DATE CONSIDERED			
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							